



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re the Application of **Steinberg**

Application No.: 10/076,858

Attorney Docket No.: R&H 03-19; ACT 183/184; DN: 51969

Filed: February 14, 2002

For: **MICROMACHINED STRUCTURES  
MADE BY COMBINED WET AND DRY  
ETCHING**

Examiner: Stephen J. Stein

Group Art Unit: 1775

**CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8(a)**

I hereby certify that this Correspondence is being deposited on the date identified below with the United States Postal Service as first-class mail in an envelope properly addressed to Commissioner for Patents, Alexandria, VA 22313-1450

8-4-2004  
Date of Certificate

Cristin Donahue  
Cristin Donahue

Commissioner for Patents  
Alexandria, VA 22313-1450

**INFORMATION DISCLOSURE STATEMENT  
UNDER 37 C.F.R. § 1.97**

In compliance with the duty of disclosure set forth in 37 C.F.R. § 1.56, Applicants are submitting herewith a Form PTO-1449 and a copy of the references listed thereon.

This Information Disclosure Statement is being filed with a Request for Continued Examination. Accordingly, there is no fee required under.

Applicants respectfully request full and proper consideration of the listed information during examination of the application, and that the listed information be printed on any patent that issues therefrom.

Respectfully submitted,

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Enclosures - Form PTO-1449

Copies of References listed on PTO -1449



# INFORMATION DISCLOSURE STATEMENT

Complete if known

Application Number: 10/076,858

Filing Date: February 14, 2002

First Named Inventor: Steinberg

Group Art Unit: 1775

Examiner Name: Stephen J. Stein

SHEET 1 OF 1

Attorney Docket Number: R&H 03-19

## UNITED STATES PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	PATENT NUMBER	ISSUE DATE MM-DD-YYYY	FIRST NAMED INVENTOR
		4810557	03/07/1989	Blonder
		4837129	06/06/1989	Frisch et al.
		4863560	09/05/1989	Hawkins
		4904036	02/27/1990	Blonder
		4938841	07/03/1990	Shahar et al.
		4957592	09/18/1990	O'Neill
		5338400	08/16/1994	Jerman
		5478438	12/26/1995	Nakanishi et al.
		5479426	12/26/1995	Nakanishi et al.
		5611006	03/11/1997	Tabuchi
		5911021	06/08/1999	MacDonald et al.
		6132107	10/17/2000	Morikawa
		6187515	02/13/2001	Tran et al.
		6257772	07/10/2001	Nakanishi et al.
		6553173	04/22/2003	Goto
		6567590	05/20/2003	Okada et al.
		US 2002/0195417	12/26/2002	Steinberg
		US 2003/0020130	01/30/2003	Steinberg et al.
		US 2003/0067069	04/10/2003	Steinberg et al.
		US 2003/0021572	01/30/2003	Steinberg

## FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	DOCUMENT NUMBER	COUNTRY OR REGION	DATE OF PUBLICATION MM-DD-YYYY	FIRST NAMED INVENTOR OR APPLICANT

## OTHER PRIOR ART - NON-PATENT DOCUMENTS

EXAMINER'S INITIALS	CITE NO.	Include name of the author (in Capital Letters), title of the article (when appropriate), title of the item(book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published
		Nijdam, et al. "Etching of silicon in alkaline solutions: a critical look at the {111} minimum," MESA
		Oosterbroek, et al. "New design methodologies in <111> oriented silicon wafers," MESA
		Suchtelen, et al. "Simulation of Anisotropic Wet-Chemical Etching Using a Physical Model," MESA

EXAMINER'S SIGNATURE	DATE CONSIDERED

**EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP §609. Draw a line through citation if citation not in conformance and reference not considered. Include a copy of this form with next communication to applicant.